A semiconductor device package including a substrate, first and second solder joints, a die pad, leads and enhancement elements surrounding the die pad, a chip electrically connected to the leads, and a package body encapsulating the chip, portions of the leads, and portions of the enhancement elements, but leaving exposed at least one side surface of each enhancement element. Side surfaces of the enhancement elements and the package body are coplanar. The substrate includes first pads corresponding to the leads and second pads corresponding to the enhancement elements. The first solder joints are disposed between the first pads and the leads. The second solder joints are disposed between the second pads and the enhancement elements. The second solder joints contact side surfaces of the enhancement elements. The surface area of the second pads is greater than the surface area of the corresponding enhancement elements.
SEMICONDUTOR DEVICE PACKAGES WITH SOLDER JOINT ENHANCEMENT ELEMENT AND RELATED METHODS

CROSS-REFERENCE TO RELATED APPLICATION

[0001] This application claims priority to Taiwan Patent Application Serial No. 100123897, filed on Jul. 6, 2011. The priority application is incorporated herein by reference in its entirety.

BACKGROUND

[0002] The present embodiments relate to semiconductor device packages, and more particularly to semiconductor device packages having a lead frame and related manufacturing methods.

DESCRIPTION OF RELATED ART

[0003] A quad-flat no-leads (QFN) package is a type of semiconductor device package having short signal traces and, thus, fast signal transmission speed. Therefore, QFN packages are well suited to chip packages with high frequency transmission (e.g., high frequency transmission through the RF bandwidth), and have become common for package applications in the wireless field, for example.

[0004] In one method of making a conventional QFN package, a lead frame having die pads and leads is provided. Chips, or dies, are configured on the die pads and electrically connected to the leads via bonding wires. The leads, the bonding wires, and the chips are encapsulated and protected by a molding compound, or encapsulant, and the bottom surfaces of the leads are exposed from the encapsulant for electrical connection to an external device, such as a printed circuit board (PCB). A singulation process is then performed to divide the structure into individual QFN packages.

[0005] After PCB surface mount, a drop test may be performed to evaluate solder joint reliability between the QFN package and the PCB. During the drop test, the solder joint is usually broken at the corners of the QFN package. Therefore, there is a need to improve the solder joint strength at the corners.

SUMMARY

[0006] One of the present embodiments comprises an electronic device. The electronic device comprises a semiconductor device package. The semiconductor device package includes a die pad, a plurality of leads disposed about the die pad, and a plurality of enhancement elements disposed about the die pad. Each of the enhancement elements has a substantially triangular outer surface and three side surfaces. The semiconductor device package further includes a chip disposed on the die pad and electrically connected to the leads, and a package body encapsulating the chip, at least portions of the leads and at least portions of the enhancement elements, but leaving exposed at least two of the side surfaces of each enhancement element. The exposed side surfaces of the enhancement elements are coplanar with side surfaces of the package body. The electronic device further comprises a plurality of first solder joints disposed between the first pads and the leads. The electronic device further comprises a plurality of second solder joints disposed between the second pads and the enhancement elements. A surface area of each of the second pads is larger than a surface area of a corresponding one of the enhancement elements. The second solder joints contact the side surfaces of the enhancement elements.

[0007] Another of the present embodiments comprises an electronic device. The electronic device comprises a semiconductor device package. The semiconductor device package includes a die pad and a plurality of leads disposed about the die pad. The semiconductor device package further includes a plurality of enhancement elements disposed symmetrically about the die pad. Each enhancement element including substantially rectangular inner and outer surfaces. The semiconductor device package further includes a chip disposed on the die pad and electrically connected to the leads, and a package body encapsulating the chip, at least portions of the leads and at least portions of the enhancement elements, but leaving exposed at least one side surface of each enhancement element. The exposed side surfaces of the enhancement elements are coplanar with side surfaces of the package body. The electronic device further comprises a substrate including a plurality of first pads corresponding to the leads and a plurality of second pads corresponding to the enhancement elements. The electronic device further comprises a plurality of first solder joints disposed between the first pads and the leads. The electronic device further comprises a plurality of second solder joints disposed between the second pads and the enhancement elements. The enhancement elements include first enhancement elements disposed at corners of the package body and second enhancement elements disposed at a center of each edge of the package body. The second solder joints contact the side surfaces of the enhancement elements.

[0008] Another of the present embodiments comprises a method of manufacturing an electronic device. The method comprises providing a semiconductor device package. The semiconductor device package comprises a die pad, a plurality of leads surrounding the die pad, and a plurality of enhancement elements surrounding the die pad. The semiconductor device package further comprises a chip disposed on the die pad and electrically connected to the leads, and a package body encapsulating the chip, portions of the leads and portions of the enhancement elements, but leaving exposed at least a side surface of each enhancement element. The side surface of each enhancement element is coplanar to the side surface of the package body. The method further comprises providing a substrate. The substrate comprises a plurality of first pads corresponding to the leads and second pads corresponding to the enhancement elements. The method further comprises mounting the semiconductor device package to the substrate by first and second solder joints. The first solder joints are disposed between the first pads and the leads. The second solder joints are disposed between the second pads and the enhancement elements. The area of each of the second pads is greater than the area of each of the corresponding enhancement elements.

BRIEF DESCRIPTION OF THE DRAWINGS

[0009] FIG. 1A is a bottom plan view illustrating one embodiment of the present semiconductor device packages;

[0010] FIG. 1B is a cross-sectional side view of the semiconductor device package of FIG. 1A, taken through the line 1B-1B in FIG. 1A;
FIG. 1C is a cross-sectional side view of the semiconductor device package of FIG. 1A taken through the IC-IC in FIG. 1A:

FIG. 1D is a cross-sectional side view of the semiconductor device package of FIG. 1A after PCB surface mount;

FIG. 2 is a bottom plan view illustrating another embodiment of the present semiconductor device packages;

FIG. 3 is a bottom plan view illustrating another embodiment of the present semiconductor device packages;

FIG. 4 is a bottom plan view illustrating another embodiment of the present semiconductor device packages;

FIG. 5 is a bottom plan view illustrating another embodiment of the present semiconductor device packages;

FIG. 6 is a bottom plan view illustrating another embodiment of the present semiconductor device packages;

FIG. 7A is a bottom plan view illustrating one embodiment of the present electronic devices;

FIG. 7B is a partial cross-sectional side view of the electronic device of FIG. 7A, taken through the line 7B-7B in FIG. 7A; and

FIG. 8 is a bottom plan view illustrating another embodiment of the present electronic devices.

Common reference numerals are used throughout the drawings and the detailed description to indicate the same elements. The present invention will be more apparent from the following detailed description taken in conjunction with the accompanying drawings.

DETAILED DESCRIPTION

Referring to FIGS. 1A-1C, a bottom plan view and two cross-sectional side views of a QFN semiconductor device package 100a according to one of the present embodiments is illustrated. The cross-section of the semiconductor device package 100a shown in FIG. 1B is taken along the line 1B-1B in FIG. 1A. The cross-section of the semiconductor device package 100a shown in FIG. 1C is taken along the line 1C-1C in FIG. 1A.

With reference to FIG. 1A, the semiconductor device package 100a includes a carrier 200a, a chip 300, and a molding compound 500. The carrier 200a includes a die pad 210, a plurality of leads 220 and an enhancement element 230a. The die pad 210 has a cavity 210a for disposing the chip 300. The leads 220 are disposed around the die pad 210, in which each lead 220 has a first inner surface 222 (shown in FIG. 1B) and a first outer surface 224 opposite to each other. The enhancement element 230a is disposed around the die pad 210 and continuously circumscibes the outer perimeter of the package 100a, in which the enhancement element 230a has a second inner surface 232a and a second outer surface 234a opposite to each other. A surface area of the second outer surface 234a of the enhancement element 230a is larger than a surface area of the first outer surface 224 of each of the leads 220. Further, a surface area of the second inner surface 232a is smaller than a surface area of the second outer surface 234a. The shapes of the second inner surface 232a and the second outer surface 234a of the enhancement element 230a may both be, for example, annular when viewed in upper or lower plan view.

With reference to FIG. 1B, metal plating layers 223, 225 may be provided on the first inner surface 222 and the first outer surface 224. The metal layers 223, 225 may be formed from titanium/copper (Ti/Cu), nickel/gold (Ni/Au), or other suitable metals, alloys, or sequences of metals and/or alloys, such as, but not limited to Cr/Cr—Cu/Cu, Ti/Ni—V/Cu, Ti/W, or Ti/W/Au.

With continued reference to FIG. 1B, the chip 300 is disposed on the die pad 210 of the carrier 200a. The semiconductor device package 100a further includes a plurality of bonding wires 400 that electrically connect the chip 300 to the first inner surfaces 222 of the leads 220. The bonding wires 400 may also electrically connect the chip 300 to the die pad 210. The molding compound 500 encapsulates the chip 300, the bonding wires 400, and the first inner surfaces 222 of the leads 220, but leaves exposed the first outer surfaces 224 of the leads 222 and the lower surface of the die pad 210.

With reference to FIG. 1C, as discussed above, the enhancement element 230a has the second inner surface 232a and the second outer surface 234a opposite to each other. The bonding wires 400 may electrically connect the chip 300 to the second inner surface 232a of the enhancement element 230a. The molding compound 500 further encapsulates the second inner surface 232a of the enhancement element 230a, but leaves exposed the second outer surface 234a of the enhancement element 230a.

Referring to FIG. 1D, a cross-sectional side view of the semiconductor device package 100a after PCB surface mount is illustrated. The first outer surfaces 224 of the leads 220 and the second outer surface 234a of the enhancement element 230a are mounted to a PCB 10 by solder 600. Advantageously, since the enhancement element 230a increases the solder contact area and solder capacity so as to enhance the connection strength, it can improve the solder joint reliability between the semiconductor device package 100a and the PCB 10. The solder 600 can be formed on the semiconductor device package 100a by a dip soldering process, a solder printing process, or an electroless plating process, for example, or any other process for PCB surface mount. Alternatively, the solder 600 can be formed on the PCB 10 by a dispensing process, a screen printing process or a stencil printing process, for example, or any other process for PCB surface mount.

Referring to FIG. 2, a bottom plan view of a semiconductor device package 100b according to another of the present embodiments is illustrated. The package 100b is similar to the semiconductor device package 100a of FIG. 1A, except that an enhancement element 230b of the package 100b includes a plurality of enhancement element portions 236b. The enhancement element portions 236b are located at the corners C of the carrier 200b, and symmetrically disposed about the die pad 210 as a center. Each enhancement element portion 236b has an outer surface 237b and an inner surface 237b opposite to each other. The shape of each surface 237b, 237b is substantially triangular, and edges of the outer surfaces 237b are substantially aligned with lateral edges of the molding compound 500. However, a surface area of each outer surface 237b is larger than a surface area of its corresponding inner surface 237b, so that edges of the inner surfaces 237b are recessed from, or not substantially aligned with, lateral edges of the molding compound 500. Further, the surface area of each outer surface 237b of each enhancement element portion 236b is larger than a surface area of the first outer surface 224 of each lead 220.

Referring to FIG. 3, a bottom plan view of a semiconductor device package 100c according to another of the present embodiments is illustrated. The semiconductor device package 100c is similar to the semiconductor device
package 100b of FIG. 1B, except that an outer surface 237c and an inner surface 237c' of each enhancement element portion 236c is substantially circular. A surface area of each outer surface 237c is larger than a surface area of each inner surface 237c'. The surface area of the outer surface 237c of each enhancement element portion 236c is larger than the surface area of the first outer surface 224 of each lead 220.

[0030] Referring to FIG. 4, a bottom plan view of a semiconductor device package 100d according to another of the present embodiments is illustrated. The semiconductor device package 100d is similar to the semiconductor device package 100c of FIG. 3, except that an enhancement element 236d of the semiconductor device package 100d includes a plurality of first enhancement element portions 236d and a plurality of second enhancement element portions 238d. The first enhancement element portions 236d are similar to the first enhancement element portions 236c of FIG. 3. The second enhancement element portions 238d are connected to a periphery of the die pad 210 at a center of each edge thereof, symmetrically disposed, and extend to the edges of the carrier 200d. Each second enhancement element portion 238d has a second outer surface 239d and a second inner surface 239d' opposite to each other. The shapes of the second outer surfaces 239d and the shapes of the second inner surfaces 239d' are substantially rectangular, and the surface area of the second outer surface 239d of each second enhancement element portion 238d is larger than the surface area of the first outer surface 224 of each lead 220.

[0031] Referring to FIG. 5, a bottom plan view of a semiconductor device package 100e according to another of the present embodiments is illustrated. The semiconductor device package 100e is similar to the semiconductor device package 100c of FIG. 4, except that the first enhancement element portions 236d are omitted.

[0032] Referring to FIG. 6, a bottom plan view of a semiconductor device package 100f according to another of the present embodiments is illustrated. The semiconductor device package 100f is similar to the semiconductor device package 100a of FIG. 1A, except that an enhancement element 230f of the semiconductor device package 100f includes a plurality of first enhancement element portions 236f and a plurality of second enhancement element portions 238f. The first enhancement element portions 236f are located at the corners C of the carrier 200f and are symmetrically disposed about the die pad 210 as a center. The second enhancement element portions 238f are symmetrically disposed at a center of each edge of the carrier 200f with the die pad 210 as a center. Each first enhancement element portion 236f has a first outer surface 237f and a first inner surface 237f' opposite to each other. The shapes of the first outer surfaces 237f and the first inner surfaces 237f' are substantially rectangular, and edges of the first outer surfaces 237f are substantially aligned with lateral edges of a molding compound 500. However, a surface area of each first outer surface 237f is larger than a surface area of its corresponding first inner surface 237f', so that edges of the second inner surfaces 239f are recessed from, or not substantially aligned with, lateral edges of the molding compound 500. Each second enhancement element portion 238f has a second outer surface 239f and a second inner surface 239f' opposite to each other. The shapes of the second outer surfaces 239f and the second inner surfaces 239f' are substantially rectangular. Edges of the second outer surfaces 239f of the second enhancement element portions 238f are substantially aligned with lateral edges of the molding compound 500. However, a surface area of each second outer surface 239f is larger than a surface area of its corresponding second inner surface 239f', so that edges of the second inner surfaces 239f' are recessed from, or not substantially aligned with, lateral edges of the molding compound 500. A surface area of each outer surface 238f/239f of each enhancement element portion 238f/239f is larger than a surface area of each first outer surface 274 of each lead 220.

[0033] In alternative embodiments, the enhancement elements 230a: 230b: 230c: 236a: 236b: 236c: 236f may be changed to other forms and/or shapes. However, it is preferred that the surface areas of the second outer surfaces 234a: 237b: 237c: 237d: 237e: 237f: 239d: 239f of the enhancement elements 230a: 230b: 230c: 236a: 236b: 236c: 236f are larger than the surface areas of the first outer surface 224 of each lead 220. The ratio of the surface area of each of the outer surfaces of the enhancement elements to the surface area of the outer surface of each lead is larger than or equal to 1.4. This configuration can enhance the connection strength and improve the solder joint reliability between the semiconductor device package and the PCB.

[0034] Referring to FIG. 7A, a bottom plan view of an electronic device 700a according to another of the present embodiments is illustrated. The electronic device 700a includes the semiconductor device package 100b of FIG. 2 and a PCB 20a. However, in alternative embodiments, the semiconductor device package 100b may be replaced by any other semiconductor device package, such as those 100a: 100c: 100f: 100e: 100g described above.

[0035] The PCB 20a includes a plurality of enhancement pads 40a, which are located at the corners C of the carrier 200a, and are symmetrically disposed about the die pad 210 as a center. Positions of the enhancement pads 40a of the PCB 20a correspond to positions of the enhancement element portions 236b of the semiconductor device package 100b. The surface area of each enhancement pad 40a is larger than the surface area of the outer surface 237b of each first enhancement element portion 236b.

[0036] Referring to FIG. 7B, a partial cross-sectional side view of the electronic device 700a of FIG. 7A is illustrated. The PCB 20a includes a plurality of bonding pads 30a, the enhancement pads 40a and a solder mask layer 50. The solder mask layer 50 covers the upper surface of the PCB 20a and exposes portions 32a: 42a of the bonding pads 30a and the enhancement pads 40a, respectively. The semiconductor device package 100b is mounted to the PCB 20a by the solder 600.

[0037] The surface area of the exposed surface 42a of the enhancement pad 40a is larger than the surface area of the exposed surface 32a of the bonding pad 30a. Positions of the bonding pads 30a correspond to positions of the leads 220. Positions of the enhancement pads 40a correspond to positions of the enhancement elements 230b. The enhancement pads 40a extend outside the carrier 200b of the semiconductor device package 100b in the direction away from the chip 300. The exposed surface 42a of each enhancement pad 40a has a width Wd in the direction away from the chip 300. The outer surface 237b of the enhancement element portion 236b of the semiconductor device package 100b has a width Wb in the same direction, and the ratio (Wd/Wb) is preferably greater than or equal to 1.3.

[0038] The solder 600 is disposed between the leads 220 of the semiconductor device package 100b and the bonding pads 30a of the PCB 20a. Although not shown in FIG. 7B, the
solder 600 may cover the entire surface of each lead 220 that is exposed from the molding compound 500. The solder 600 is also disposed between the enhancement element portions 236b and the enhancement pad portions 44a. Since the enhancement pad 40a extends outside the enhancement element portions 236b, when the ratio (Wd/Wb) is greater than or equal to 1.3, the solder 600 can overflow to contact side surfaces 237b of the enhancement element portions 236b. The overflowed solder 600 can provide additional joint strength and improve the solder joint reliability between the semiconductor device package 100b and the PCB 20a due to the increased contact area between the solder 600 and the package 100.

[0039] Referring to FIG. 8, a bottom plan view of an electronic device 700b according to another of the present embodiments is illustrated. The electronic device 700b is similar to the electronic device 700a of FIG. 7A, except that an enhancement pad 40b of a PCB 20b includes a plurality of first and second enhancement pad portions 45a, 46b. An enhancement element 230b of a carrier 200b of a semiconductor device package 100b includes a plurality of first and second enhancement element portions 236b, 238b.

[0040] The first enhancement element portions 236b are located at the corners C of the carrier 200b and symmetrically disposed about the die pad 210 as a center. The second enhancement element portions 238b are symmetrically disposed at the centers of the edges of the carrier 200b with the die pad 210 as a center. The shapes of the outer surfaces 237b and the inner surfaces 237b’ of the first enhancement element portions 236b are substantially triangular. The shapes of the outer surfaces 239b and the inner surfaces 239b’ of the second enhancement element portions 238b are substantially semicircular.

[0041] Positions of the second enhancement pad portions 46b correspond to positions of the second enhancement element portions 238b. A surface area of the exposed surface of the second enhancement pad portion 46b is larger than a surface area of the outer surface 239b of the second enhancement element portion 238b. In addition, the edges of the outer surfaces 239b of the second enhancement element portions 238b are substantially aligned with the lateral edges of the molding compound 500. Positions of the first and second enhancement pad portions 45a, 46b correspond to positions of the first and second enhancement element portions 236b, 238b. The first and second enhancement pad portions 45a, 46b extend outside the carrier 200b of the semiconductor device package 100b in the direction away from the chip 300. The surface area of the exposed surfaces of the first and second enhancement pad portions 45a, 46b are larger than the surface area of the outer surfaces the first and second enhancement element portions 236b, 238b respectively. This configuration allows the solder 600 to overflow to the side surfaces of the first and second enhancement element portions 236b, 238b. The overflowed solder 600 can provide additional joint strength and improve the solder joint reliability between the semiconductor device package 100b and the PCB 20b due to the increased contact area between the solder 600 and the package 100b.

[0042] While the invention has been described and illustrated with reference to specific embodiments thereof, these descriptions and illustrations do not limit the invention. It should be understood by those skilled in the art that various changes may be made and equivalents may be substituted without departing from the true spirit and scope of the invention as defined by the appended claims. The illustrations may not necessarily be drawn to scale. There may be distinctions between the artistic renditions in the present disclosure and the actual apparatus due to manufacturing processes and tolerances. There may be other embodiments of the present invention which are not specifically illustrated. The specification and the drawings are to be regarded as illustrative rather than restrictive. Modifications may be made to adapt a particular situation, material, composition of matter, method, or process to the objective, spirit and scope of the invention. All such modifications are intended to be within the scope of the claims appended hereto. While the methods disclosed herein have been described with reference to particular operations performed in a particular order, it will be understood that these operations may be combined, sub-divided, or reordered to form an equivalent method without departing from the teachings of the invention. Accordingly, unless specifically indicated herein, the order and grouping of the operations are not limitations of the invention.

What is claimed is:

1. An electronic device, comprising:
   a semiconductor device package including
   a die pad;
   a plurality of leads disposed about the die pad;
   a plurality of enhancement elements disposed about the die pad, wherein each of the enhancement elements has a substantially triangular outer surface and three side surfaces;
   a chip disposed on the die pad and electrically connected to the leads; and
   a package body encapsulating the chip, at least portions of the leads and at least portions of the enhancement elements, but leaving exposed at least two of the three surfaces of each enhancement element, wherein the exposed side surfaces of the enhancement elements are coplanar with side surfaces of the package body;
   a substrate including a plurality of first pads corresponding to the leads and a plurality of second pads corresponding to the enhancement elements;
   a plurality of first solder joints disposed between the first pads and the leads; and
   a plurality of second solder joints disposed between the second pads and the enhancement elements;
   wherein a surface area of each of the second pads is larger than a surface area of a corresponding one of the enhancement elements; and
   wherein the second solder joints contact the side surfaces of the enhancement elements.

2. The electronic device of claim 1, wherein a ratio of a width of each of the second pads to a width of each of the enhancement elements is greater than or equal to 1.3.

3. The electronic device of claim 1, wherein the leads have first outer surfaces exposed from the package body, the enhancement elements have second outer surfaces exposed from the package body, and a width of each of the second outer surfaces is greater than a width of each of the first outer surfaces.

4. The electronic device of claim 1, further comprising a solder mask layer covering portions of the substrate, but leaving the first and second pads exposed.

5. The electronic device of claim 1, wherein the enhancement elements are disposed at corners of the semiconductor device package.
6. The electronic device of claim 1, wherein the enhancement elements are symmetrically disposed about the die pad as a center.

7. The electronic device of claim 1, wherein each enhancement element further comprises a substantially triangular inner surface, and each of the inner surfaces has a lesser surface area than its corresponding outer surface.

8. The electronic device of claim 7, further comprising metal plating layers on the inner and outer surfaces of the enhancement elements.

9. The electronic device of claim 8, wherein the metal plating layers comprise materials selected from at least one of titanium/copper (Ti/Cu), nickel/gold (Ni/Au), Cr/Cr—Cu/Cu, TiNi—V, TiNi—V/Cu, Ti/W, and Ti/W/Au.

10. An electronic device, comprising:
    a semiconductor device package including:
    a die pad;
    a plurality of leads disposed about the die pad;
    a plurality of enhancement elements disposed symmetrically about the die pad, each enhancement element including substantially rectangular inner and outer surfaces;
    a chip disposed on the die pad and electrically connected to the leads; and
    a package body encapsulating the chip, at least portions of the leads and at least portions of the enhancement elements, but leaving exposed at least one side surface of each enhancement element, wherein the exposed side surfaces of the enhancement elements are coplanar with side surfaces of the package body;
    a substrate including a plurality of first pads corresponding to the leads and a plurality of second pads corresponding to the enhancement elements;
    a plurality of first solder joints disposed between the first pads and the leads; and
    a plurality of second solder joints disposed between the second pads and the enhancement elements;
    wherein the enhancement elements include first enhancement elements disposed at corners of the package body and second enhancement elements disposed at a center of each edge of the package body; and
    wherein the second solder joints contact the side surfaces of the enhancement elements.

11. The electronic device of claim 10, wherein a ratio of a width of each of the second pads to a width of each of the enhancement elements is greater than or equal to 1.3.

12. The electronic device of claim 10, wherein the leads have first outer surfaces exposed from the package body, the enhancement elements have second outer surfaces exposed from the package body, and a width of each of the second outer surfaces is greater than a width of each of the first outer surfaces.

13. The electronic device of claim 10, further comprising a solder mask layer covering portions of the substrate, but leaving the first and second pads exposed.

14. The electronic device of claim 10, wherein each of the enhancement element inner surfaces has a lesser surface area than its corresponding outer surface.

15. The electronic device of claim 10, further comprising metal plating layers on the inner and outer surfaces of the enhancement elements.

16. The electronic device of claim 15, wherein the metal plating layers comprise materials selected from at least one of titanium/copper (Ti/Cu), nickel/gold (Ni/Au), Cr/Cr—Cu/Cu, TiNi—V, Ti/W, and Ti/W/Au.

17. A method of manufacturing an electronic device, the method comprising:
    providing a semiconductor device package, the semiconductor device package comprising a die pad, a plurality of leads surrounding the die pad, a plurality of enhancement elements surrounding the die pad, a chip disposed on the die pad and electrically connected to the leads and a package body encapsulating the chip, portions of the leads and portions of the enhancement elements, but leaving exposed at least a side surface of each enhancement element, wherein the side surface of the enhancement elements is coplanar to the side surface of the package body;
    providing a substrate, the substrate comprising a plurality of first pads corresponding to the leads and second pads corresponding to the enhancement elements; and
    mounting the semiconductor device package to the substrate by first and second solder joints; wherein the first solder joints are disposed between the first pads and the leads, the second solder joints are disposed between the second pads and the enhancement elements, and the area of each of the second pads is greater than the area of each of the corresponding enhancement elements.

18. The manufacturing method of claim 17, wherein the second solder joints contact the side surface of each enhancement element.

19. The manufacturing method of claim 17, wherein a ratio of a width of the second pad to a width of the corresponding enhancement element is greater than or equal to 1.3.

20. The manufacturing method of claim 17, wherein the enhancement elements are symmetrically disposed about the die pad as a center.

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